



PATENT  
97-CT-174

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of:  
RAFFAELE ZAMBRANO  
Serial No.: 09/191,743  
Filed: November 13, 1998  
For: IN-SITU DEPOSITION AND  
DOPING PROCESS FOR POLY-  
CRYSTALLINE SILICON LAYERS  
AND THE RESULTING DEVICE

Group Art Unit: 2815

Examiner: C. Whitehead

**RECEIVED**

JUN 25 1999

TECHNOLOGY CENTER 2800

7/A  
6/25/99  
JPh

AMENDMENT AND ELECTION

Assistant Commissioner for Patents  
Washington, D.C. 20231

Sir:

In response to the Office Action dated April 19, 1999, the due date for response to which has been extended to June 19, 1999 by the enclosed petition for extension of time, in connection with the above-identified application, please enter and consider the following amendment and remarks.

I hereby certify that this correspondence is being deposited with the United States Postal Service with sufficient postage as first class mail in an envelope addressed to: Assistant Commissioner for Patents,

Washington, D.C. 20231, on 6/18/99  
Date of Deposit

Stephen Bongini  
Applicant, Assignee, or Representative

Stephen Bongini 6/18/99  
Signature Dated